

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE **FAX RECEIVED**

In re application of:

Group Art Unit: 1732

APR 11 2006

OFFICE OF PETITIONS

**Brian W. Baird, Michael J. Wolfe,
Richard S. Harris, Kevin P. Fahey,
Lian-Cheng Zou, and Thomas R. McNeil**

Application No. 10/017,497

Filed: December 14, 2001

For: **ULTRAVIOLET LASER ABLATIVE
PATTERNING OF MICROSTRUCTURES
IN SEMICONDUCTORS**

Date: April 11, 2006

Examiner: Dr. Stefan Staicovici

AMENDMENT C

TO THE COMMISSIONER FOR PATENTS:

Please amend the above-identified application as follows.

Amendments to the Claims are reflected in the listing of claims that begins on page 2 of this paper.

Remarks begin on page 9 of this paper.